

PIEZOELECTRIC/ELECTROSTRICTIVE ACTUATOR HAVING
AT LEAST ONE PIEZOELECTRIC/ELECTROSTRICTIVE FILM

ABSTRACT

A piezoelectric/electrostrictive actuator including a ceramic substrate (2), and at least one piezoelectric/electrostrictive actuator unit formed on at least a portion of at least one surface of the substrate, each piezoelectric/electrostrictive actuator unit having a first electrode film (4), a piezoelectric/electrostrictive film (6) and a second electrode film (8) which are laminated in the order of description, with the piezoelectric/electrostrictive actuator unit formed on the substrate by heat treatment.

FIGURE 1